



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Trung T. Doan

Serial No.: 09/652,713

Filed: August 31, 2000

For: CHEMICAL DISPENSING SYSTEM FOR
SEMICONDUCTOR WAFER PROCESSING

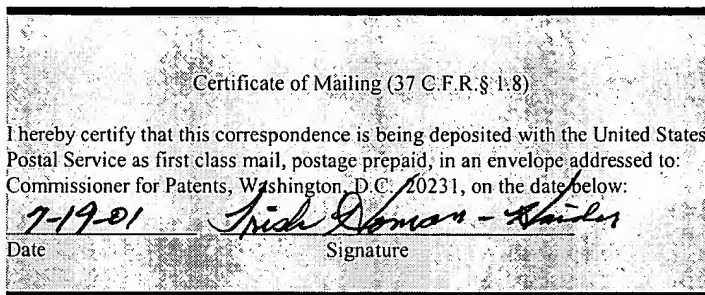
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§ Group Art Unit: 1763
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§ Examiner: Sylvia R. MacArthur
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§ Atty. Docket: 93-0421.04
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RESPONSE TO THE OFFICE ACTION OF JANUARY 19, 2001

Commissioner for Patents

Washington, D.C. 20231



Dear Sir:

Applicant herein responds to the Examiner's Office Action of January 19, 2001. Please amend the application as follows.

IN THE CLAIMS

Please cancel claims 34-35 and 41-43 without prejudice.

Please amend claim 36 to the form below.

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36. (Once amended) A device for an edge bead, comprising:

a dispenser configured to release a chemical toward said edge bead; and

a splash controller around said dispenser, physically unattached from said edge

bead, and configured to draw said chemical toward said splash controller, wherein said splash controller is configured to generate a gas pressure around said edge

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